

Notice of References Cited

Application/Control No.

10/060,944

Applicant(s)/Patent Under
Reexamination
KIKUCHI ET AL.

Examiner

Zia R. Hashmi

Art Unit

2881

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U.S. PATENT DOCUMENTS

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Name	Classification
	A	US-			
	B	US-			
	C	US-			
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FOREIGN PATENT DOCUMENTS

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NON-PATENT DOCUMENTS

*		Include as applicable: Author, Title Date, Publisher, Edition or Volume, Pertinent Pages)
	U	Ishimoto et al. " Method of Inspecting Holes Using Charged-Particle Beam ", Pub. No: 2001/0022345 A1, published 9/20/2001.
	V	Yamada et al. " Semiconductor Device Inspection Apparatus ", Pub. No: US 2002/0070738 A1, published 6/13/2002.
	W	
	X	

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